

Docket No. AM1562D1

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of

YIQIONG WANG

Confirmation No. 8856

Serial No.: 09/882,141

Examiner: Umez-Eronini

Filed: June 15, 2001

Group Art Unit: 1765

For: METHOD OF ETCHING HIGH ASPECT  
RATIO OPENINGS IN SILICONAMENDED RESPONSE UNDER 37 CFR 1.115To: Assistant Commissioner for Patents  
Washington, DC 20231*FAX RECEIVED  
JUN 12 2003  
GROUP 1765*

Sir:

In response to the office action of February 25, 2003, and a  
Notice of Non-Compliant Amendment dated June 4<sup>m</sup> 2003, please  
amend the above-identified application as follows.

**OFFICIAL****CERTIFICATE OF TRANSMISSION BY FACSIMILE (37 CFR 1.8)**

Applicant(s): YIQIONG WANG

Docket No.

AM1562D1

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Umez-EroniniGroup Art Unit  
1765

Invention: METHOD OF ETCHING HIGH ASPECT RATIO OPENINGS IN SILICON

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 GROUP 1700

I hereby certify that this Amended Response under 37 CFR 1.115 (8pp)  
(Identify type of correspondence)

is being facsimile transmitted to the United States Patent and Trademark Office (Fax. No. 703-872-9310)

on June 12, 2003

(Date)

Birgit E. Morris

(Typed or Printed Name of Person Signing Certificate)

*Birgit E. Morris*  
(Signature)

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